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#### **Enhanced Photoluminescence of GaAs Nanowires by Remote Oxygen Plasma Treatment** Dustin Tso<sup>1</sup>, Nirakar Poudel<sup>1</sup>, Shermin Arab<sup>2</sup>, Maoqing Yao<sup>2</sup>, Chongwu Zhou<sup>2</sup>, P. Daniel

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# Motivation and Introduction

• GaAs nanowires are an excellent candidate for high efficiency solar cells, nanolasers, LED applications, and integrated circuits





High surface state densities and high surface recombination velocities limit optoelectronic performance We present a novel method for GaAs surface passivation utilizing a remote oxygen plasma treatment

## Measurements and Results

Photoluminescence Spectroscopy (PL) is used to measure samples before and after the remote oxygen plasma treatment



### Remote Oxygen Plasma



Above are PL spectra taken before and after remote oxygen plasma treatment for silicon doping conditions of (a) 0.01 sccm (b) 0.1 sccm (c) 1 sccm and (d) planar GaAs



- Above are control experiments we ran. On the left is the PL spectra of planar InP wafer before and after remote oxygen plasma treatment
- On the right is the PL spectra a 0.2 sccm doped GaAs nanowire before and after plasma ashing

#### Sample Preparation

- GaAs nanowires are grown on silicon substrates using MOCVD with selective area growth
- Growth on silicon enables PL measurements to be taken without contribution from underlying substrate





Samples with different carrier concentrations are prepared by varying the partial pressure of disilane from 0.01 sccm to 1 sccm in order to increase the amount of Si dopants during different growth runs

# Conclusion and Next Steps

- We believe that the O-radicals from this remote oxygen plasma are binding to charged surface states, which passivates these surface states and results in improved PL intensity
- Enhancement is more pronounced in lightly doped nanowires, which have fewer impurities, making them more susceptible to surface recombination
- Heavily doped nanowires have negligible changes in PL intensity since the high density of impurities causes substantial non-radiative recombination in bulk material Next Steps
- Low temperature PL measurements
- Expose samples to plasma for different times (we used 2) minutes for every measurement)